

Semiconductor Fundamentals

In-Class Test 1 (2.5%)

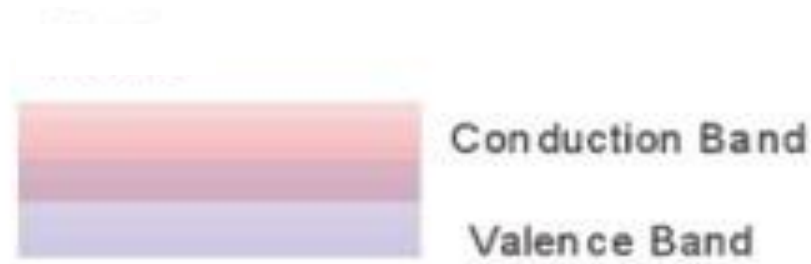
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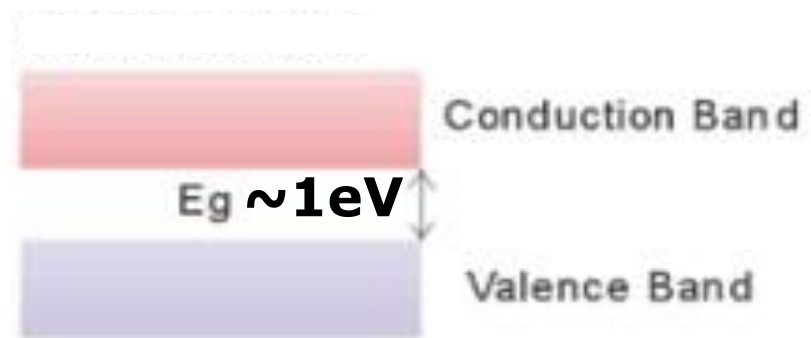
Signature:

CT1. Which one is semiconductor?

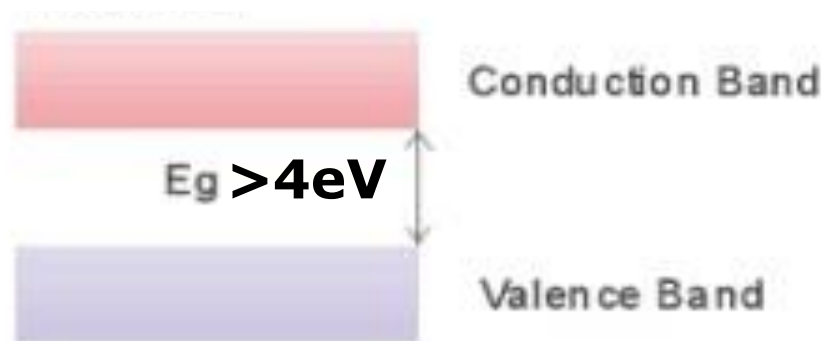
(A)



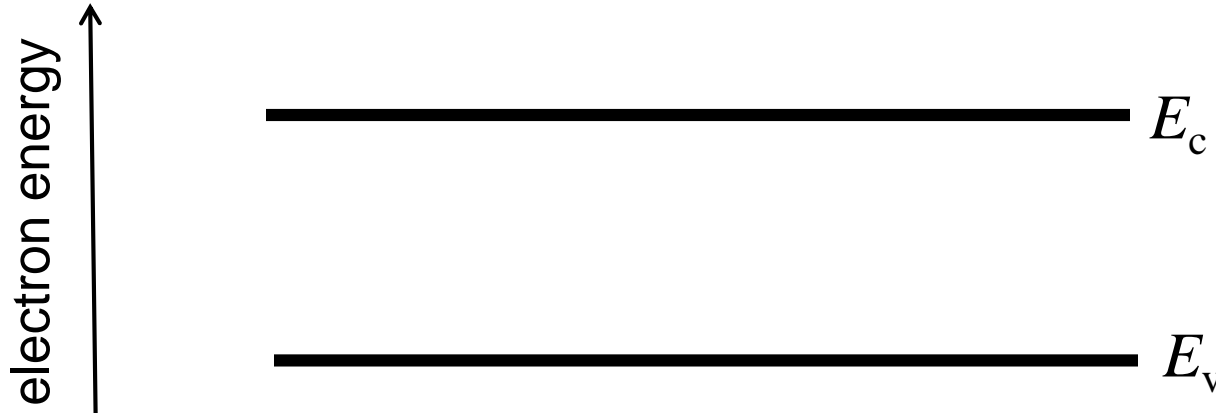
(B)



(C)



CT2. Which one is correct?



(A)

- E_v is bottom edge of the conduction band
- E_c is top edge of the valence band
- E_c and E_v are separated by the **band gap energy** E_g

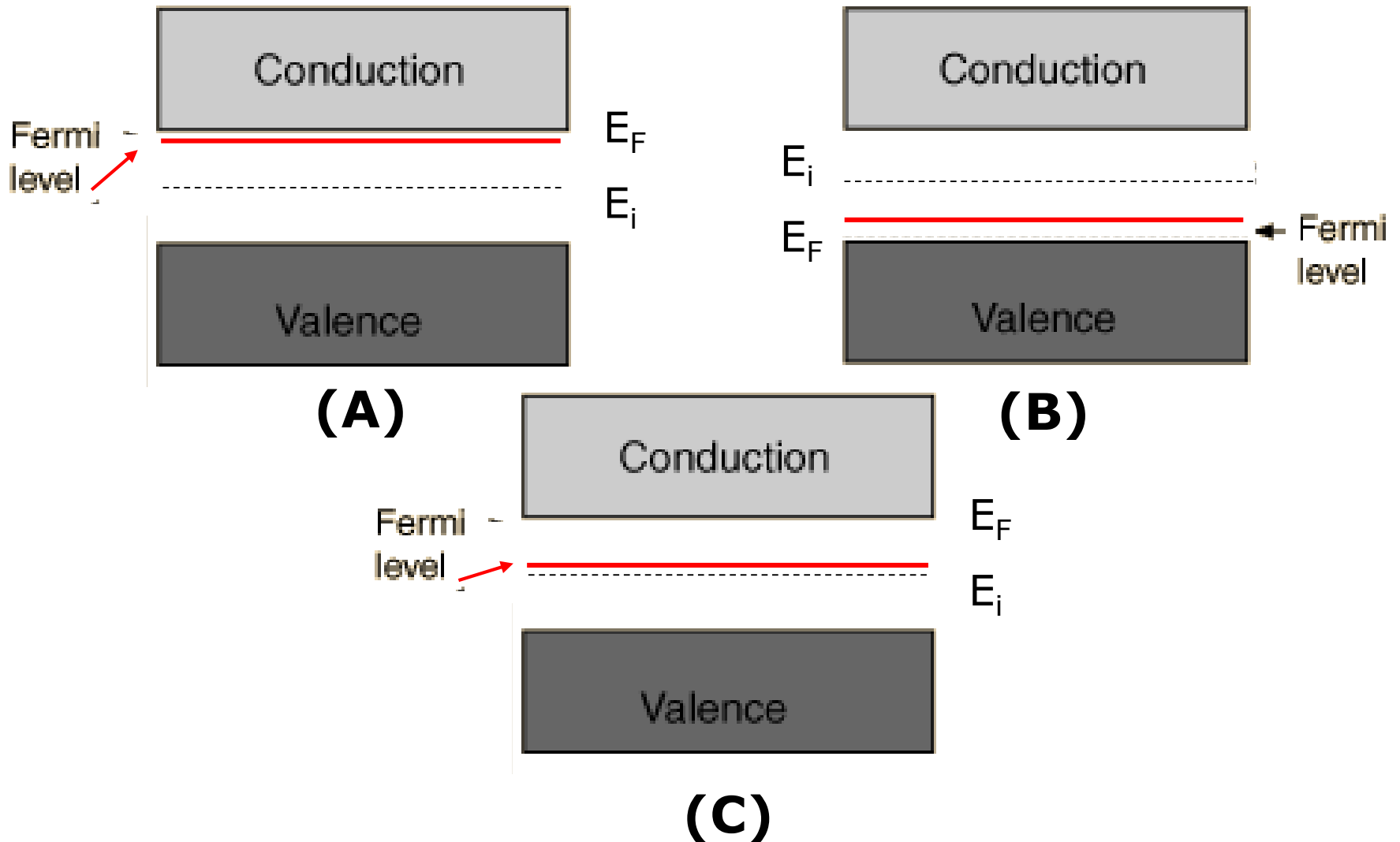
(B)

- E_c is bottom edge of the conduction **level**
- E_v is top edge of the valence **level**
- E_c and E_v are separated by the **level gap energy** E_g

(C)

- E_c is bottom edge of the conduction **band**
- E_v is top edge of the valence **band**
- E_c and E_v are separated by the **band gap energy** E_g

CT3. Which one is P-Type Semiconductor?

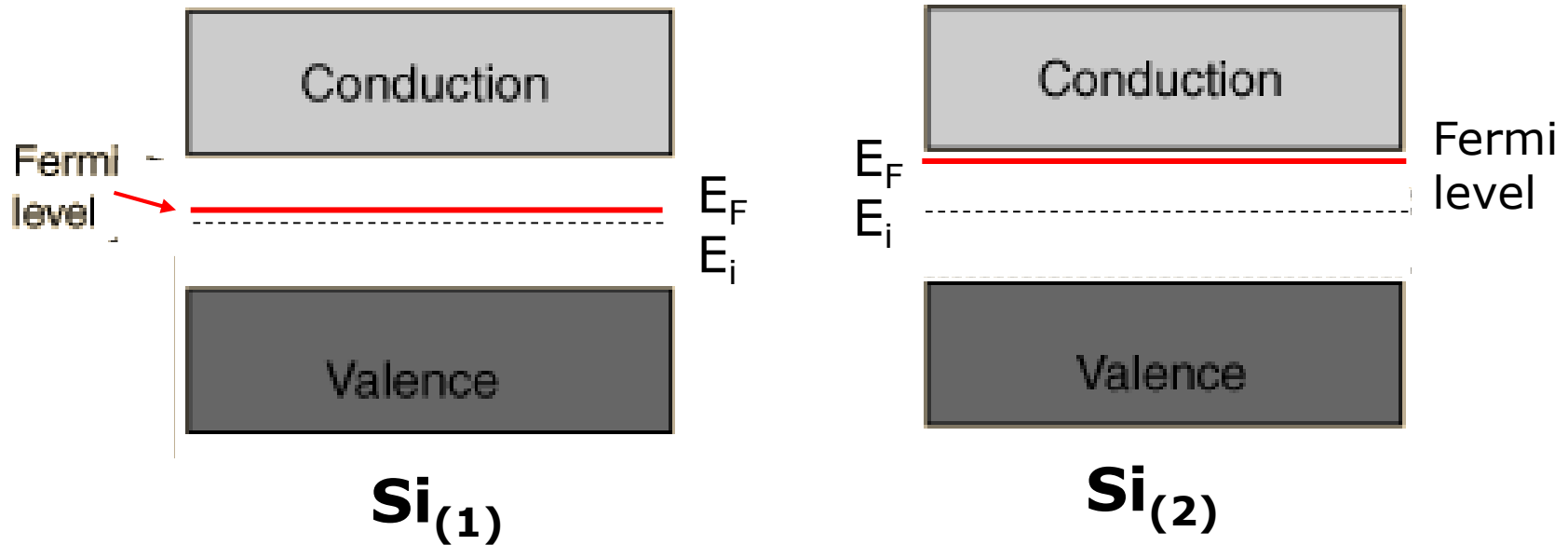


CT4

Energy band diagrams of two silicon materials, $\text{Si}_{(1)}$ and $\text{Si}_{(2)}$, are shown below and $(E_F - E_V)_{(1)} > (E_F - E_V)_{(2)}$,

Which one is true, compared with $\text{Si}_{(2)}$?

- (A) $\text{Si}_{(1)}$ is a stronger p-type. (B) $\text{Si}_{(1)}$ is a weaker p-type.
(C) $\text{Si}_{(1)}$ is a weaker n-type. (D) $\text{Si}_{(1)}$ is a stronger n-type.



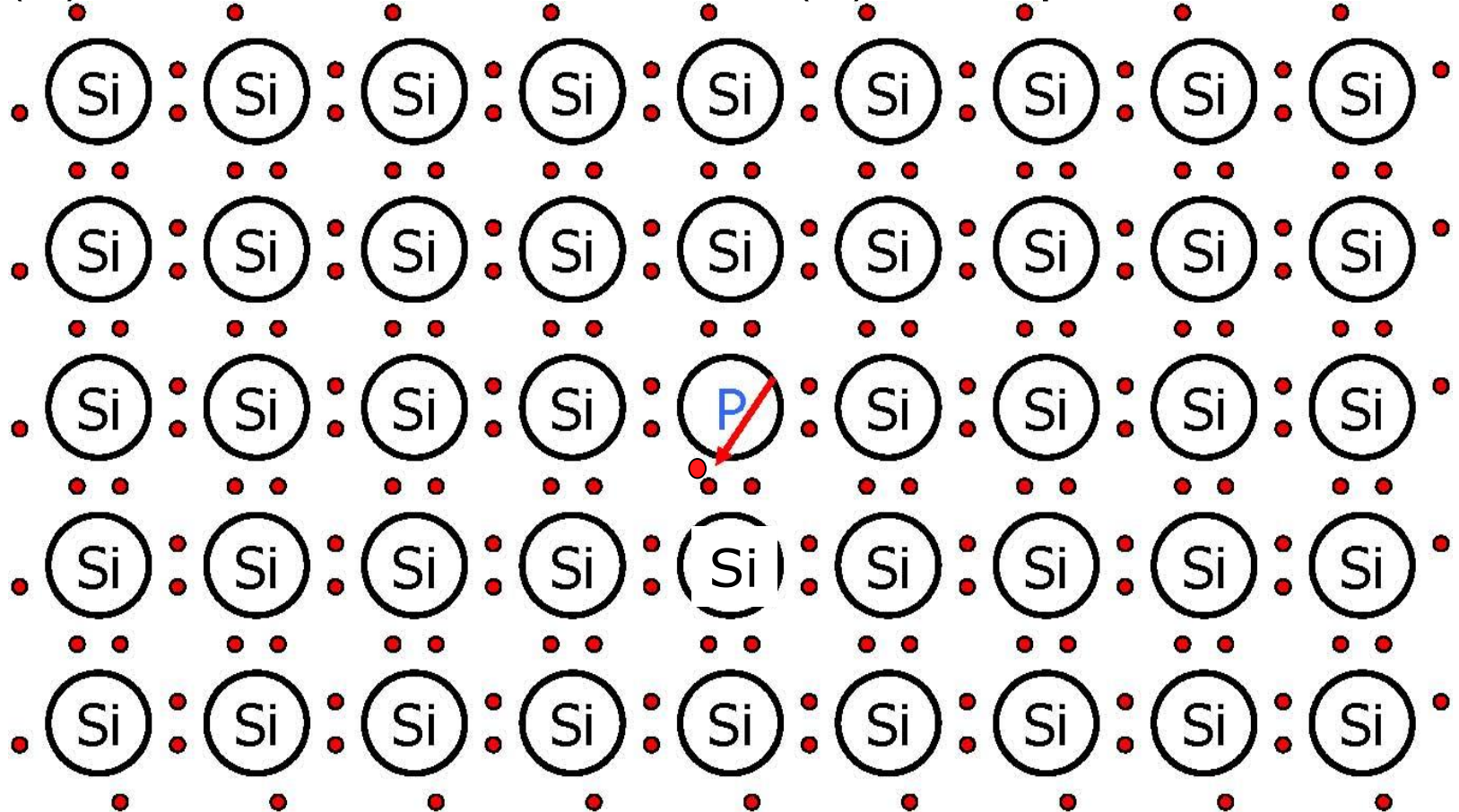
CT5. What kind of semiconductor it is ?

(A) It is an n-type semi.

(B) It is a p-type semi.

(C) It is an intrinsic semi.

(D) It is a pure semi.



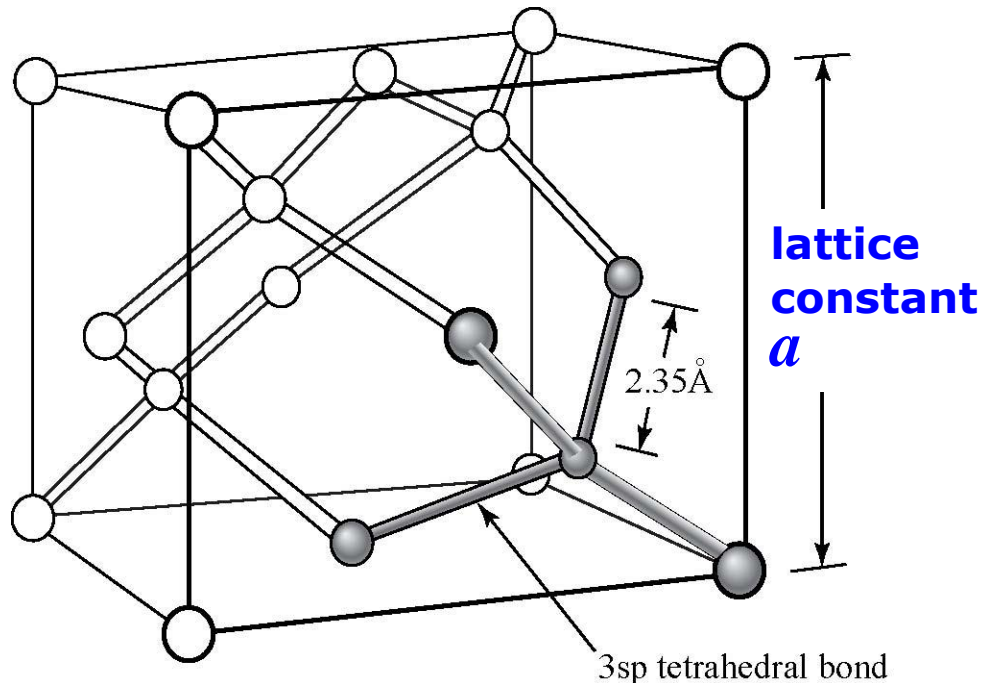
CT6. What are the correct approximate **atomic density** and **lattice constant a** respectively for silicon crystal at room temperature?

(A) 5×10^{20} & 0.54nm

(B) 5×10^{22} & 0.54nm

(C) 5×10^{22} & 54Å

(D) 5×10^{28} & 54Å



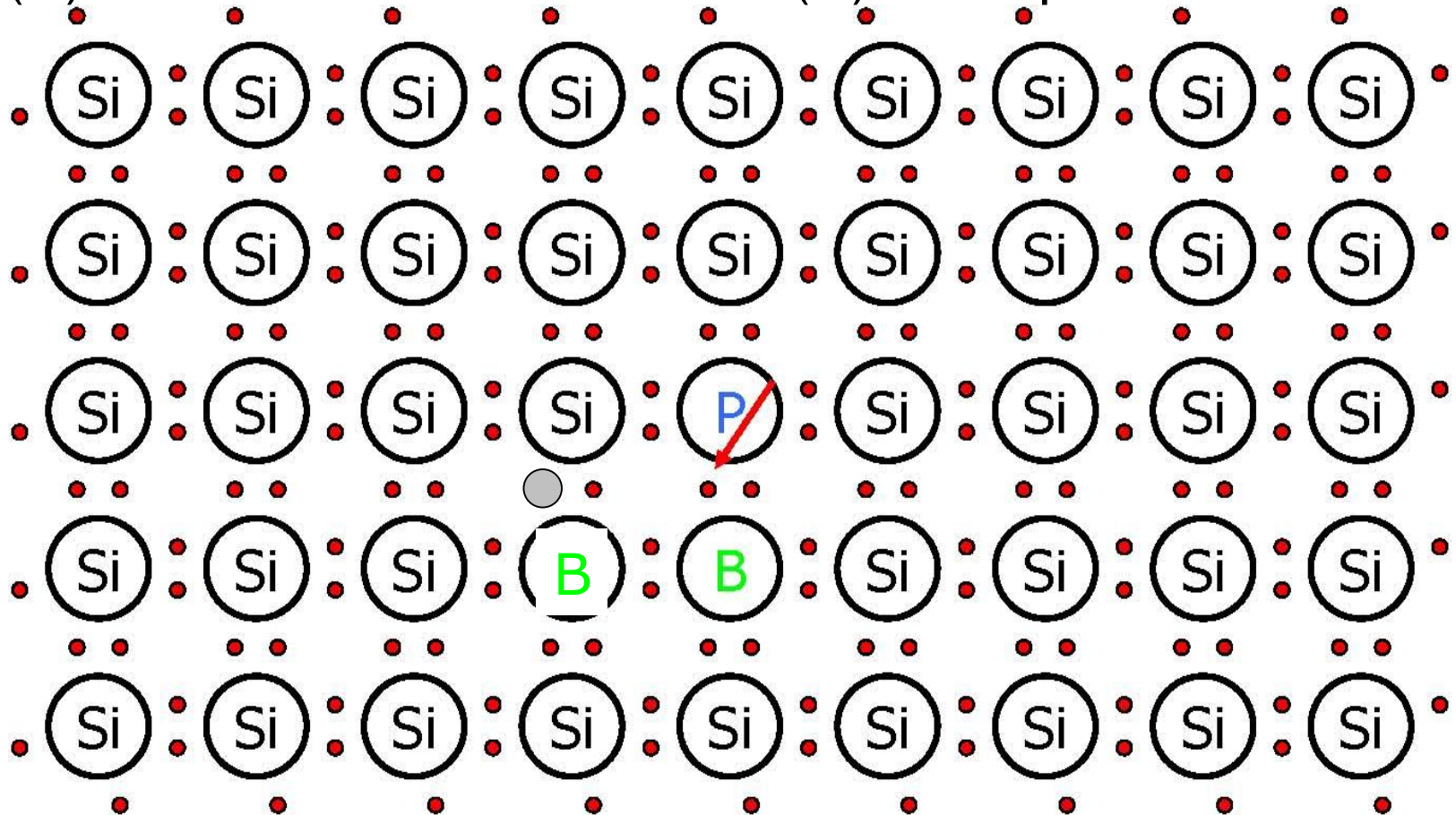
CT7. What kind of semiconductor it is ?

(A) It is an n-type semi.

(B) It is a p-type semi.

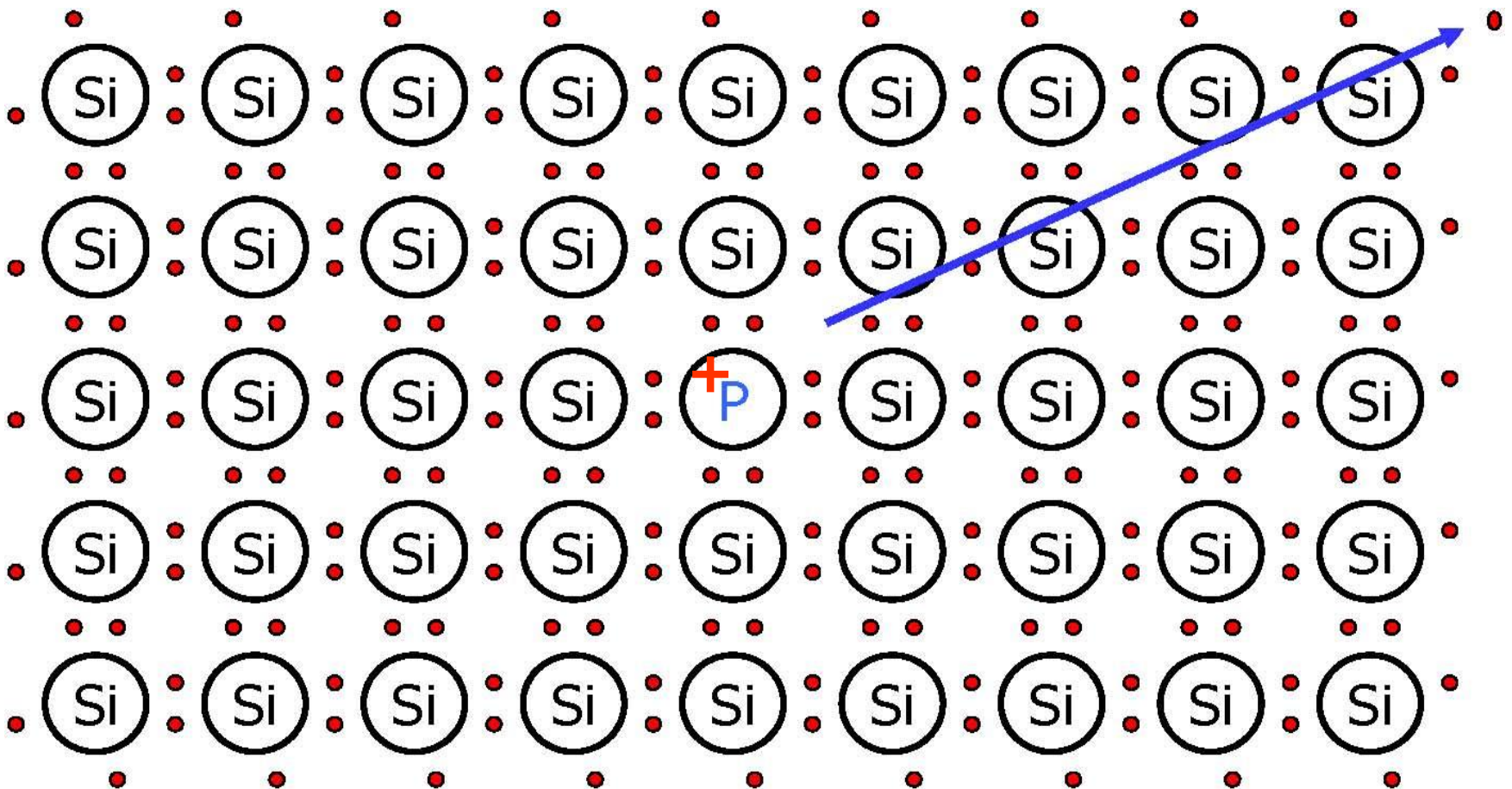
(C) It is an intrinsic semi.

(D) It is a pure semi.



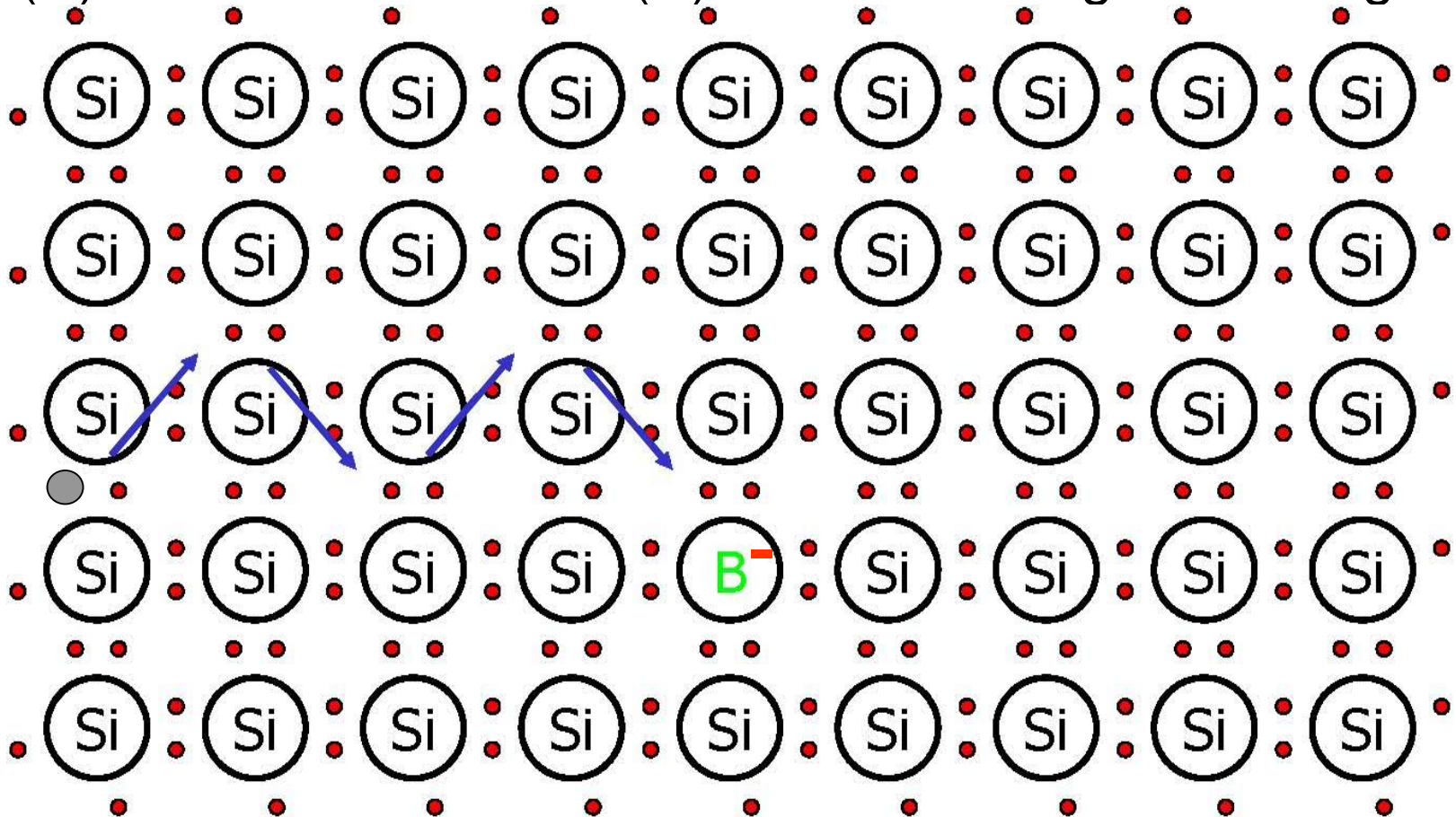
CT8. Which one is correct on P^+ ion?

- (A) It is a hole. (B) It is a mobile positive charge.
(C) It is a electron. (D) It is a fixed positive charge.



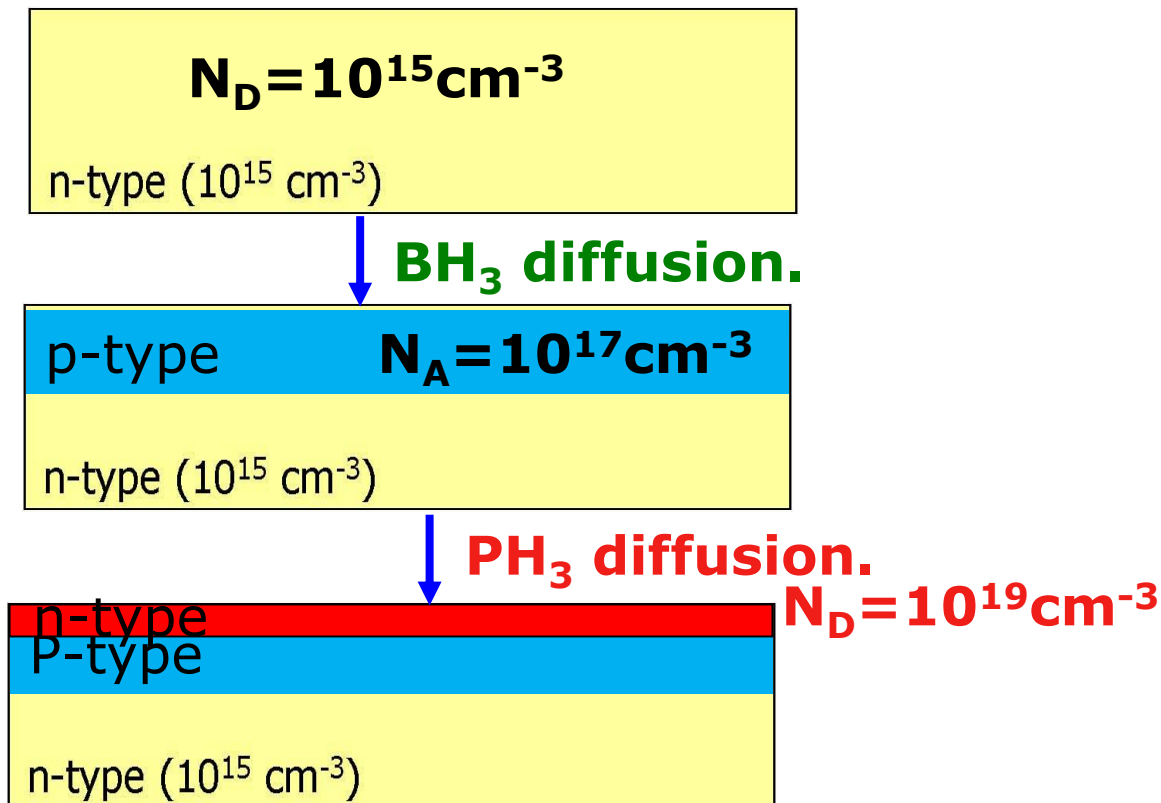
CT9. Which one is correct on B⁻ ion?

- (A) It is a hole. (B) It is a mobile negative charge.
(C) It is an electron. (D) It is a fixed negative charge.



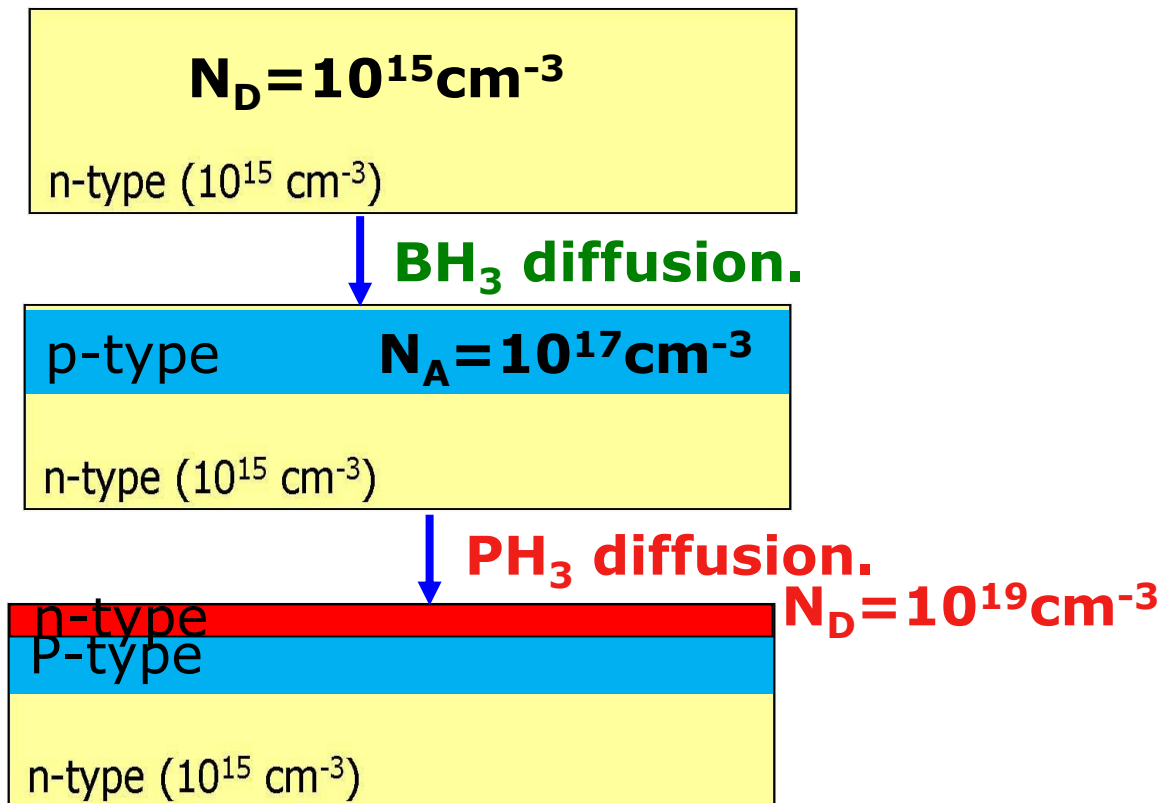
CT10. Fig. shows a formation of an npn transistor. After PH_3 diffusion, the **hole** density of the **middle** layer is

- (A) 10^{19}cm^{-3} . (B) 10^{18}cm^{-3} . (C) 10^{17}cm^{-3} .
(D) 10^{16}cm^{-3} . (E) 10^{15}cm^{-3} .



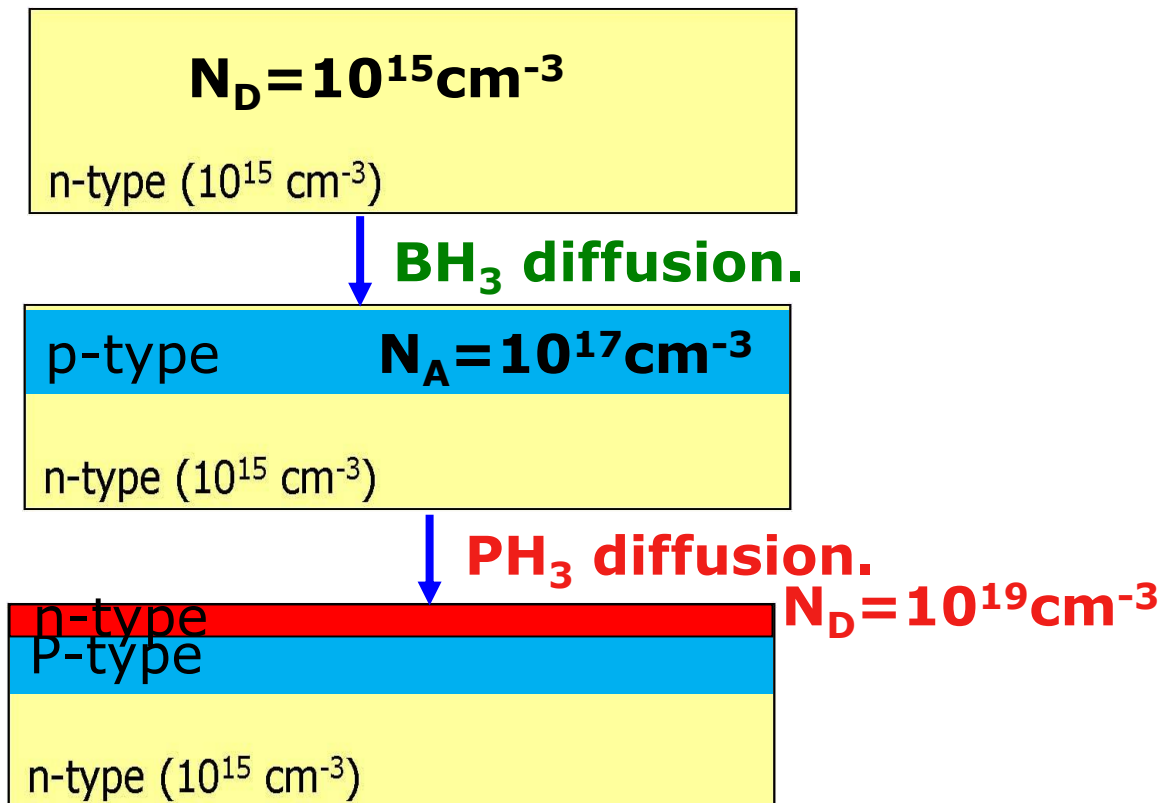
CT11. Fig. shows a formation of npn transistor.
After PH_3 diffusion, the **electron** density of the **middle** layer is

- (A) 10^{19}cm^{-3} . (B) 10^{17}cm^{-3} . (C) 10^{15}cm^{-3} .
(D) 10^3cm^{-3} . (E) 10^1cm^{-3} .



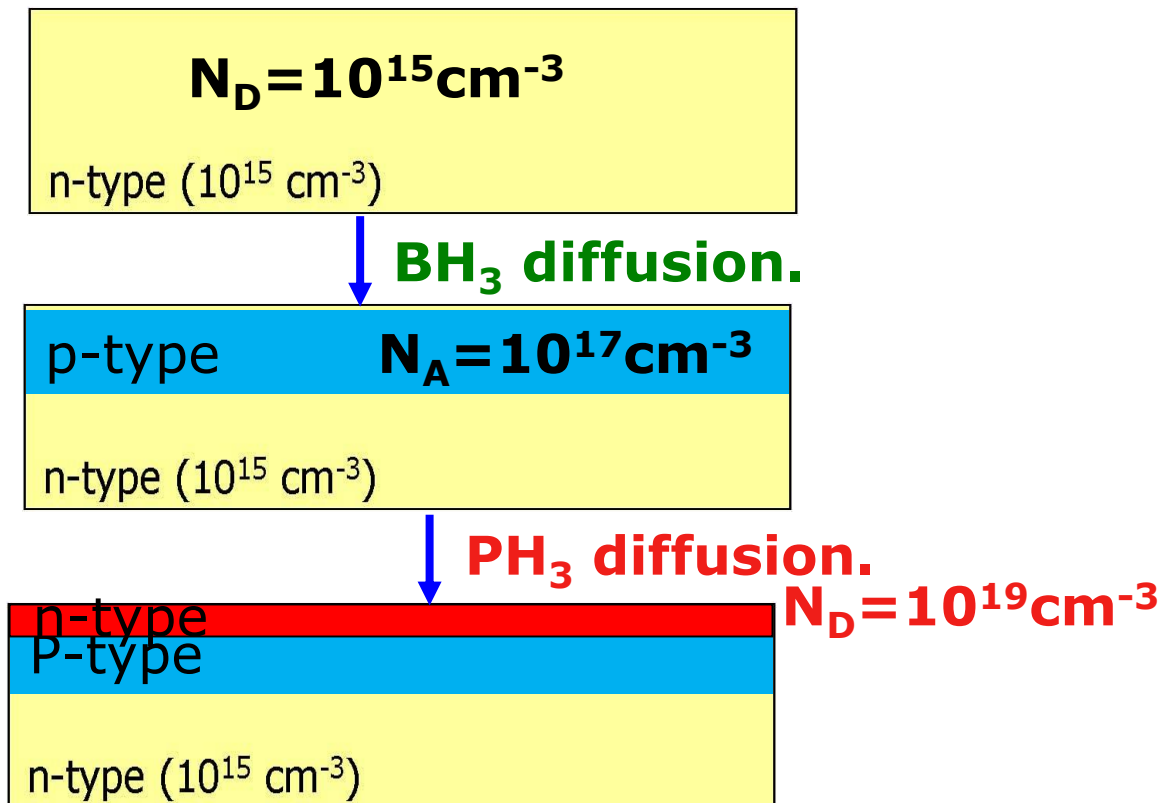
CT12. Fig. shows a formation of npn transistor.
After PH_3 diffusion, the **hole** density of the **top** layer is

- (A) 10^{19}cm^{-3} . (B) 10^{18}cm^{-3} . (C) 10^{17}cm^{-3} .
(D) 10^3cm^{-3} . (E) 10^1cm^{-3} .



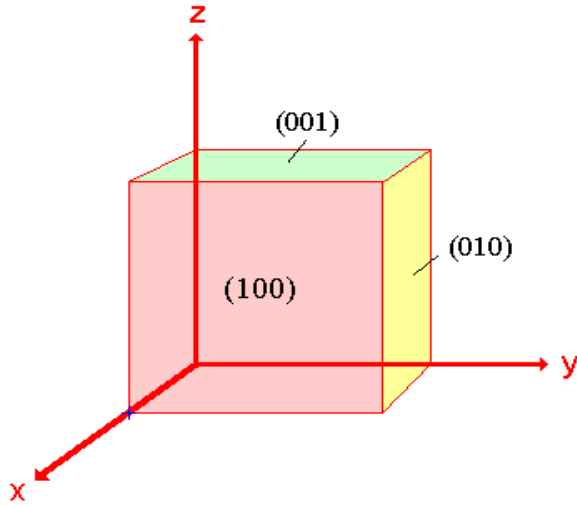
CT13. Fig. shows a formation of npn transistor. After PH_3 diffusion, the **electron** density of the **top** layer is

- (A) 10^{19}cm^{-3} . (B) 10^{18}cm^{-3} . (C) 10^{17}cm^{-3} .
(D) 10^3cm^{-3} . (E) 10^1cm^{-3} .



CT14.

Miller indices ($h\ k\ l$) for planes are defined as



(A)

h : inverse x -intercept of plane
 k : inverse y -intercept of plane
 l : inverse z -intercept of plane

or (B)

h : x -intercept of plane
 k : y -intercept of plane
 l : z -intercept of plane

CT15. There are two collision or scattering mechanisms that affect the carrier mobility μ : phonon or lattice scattering effect μ_L , and ionized impurity scattering effect μ_I , where

(A) $\mu_L \propto T^{+3/2}$ and $\mu_I \propto T^{-3/2} / N_I$

or (B) $\mu_I \propto T^{-3/2}$ and $\mu_L \propto T^{+3/2} / N_I$

or (C) $\mu_L \propto T^{-3/2}$ and $\mu_I \propto T^{+3/2} / N_I$

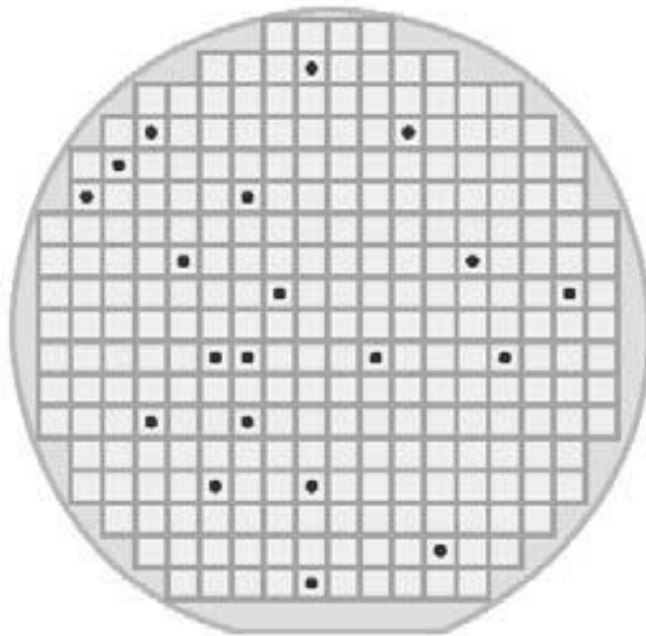
CT16. Their yields are, respectively,

(A) 92% and 70%.

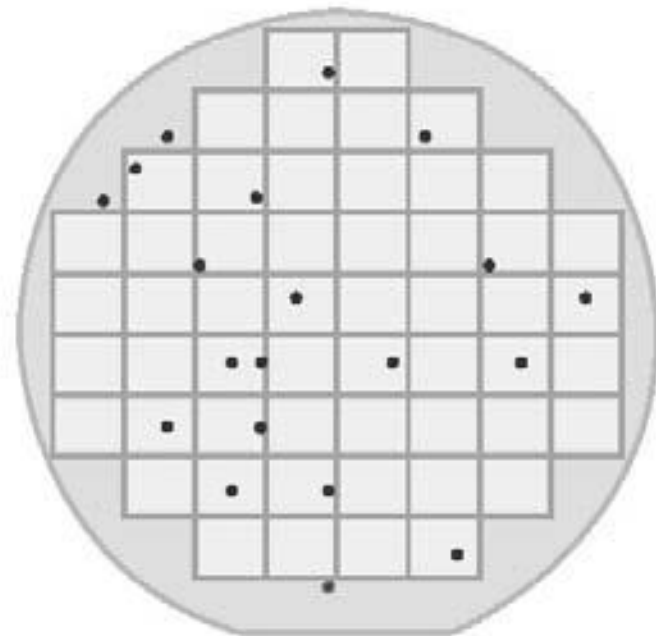
(B) 92% and 30%.

(C) 7.6% and 30%.

(D) 70 and 7.6%.



20 Bad Die
264 Gross Die



16 Bad Die
54 Gross Die

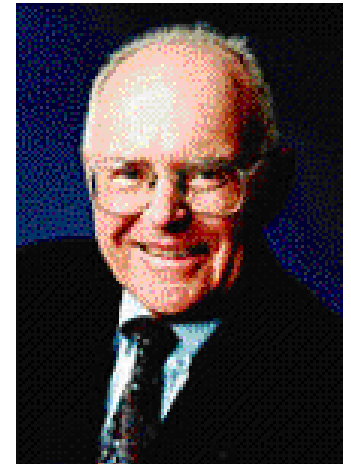
CT17. Moore's Law shows

(A) density of IC devices is doubling with *every two new generation*.

(B) the number of transistors on a chip will double *every 18 to 24 months*.

(C) Components (such as inductors) per chip will double *every 1.5 - 2 years*.

(D) semiconductor technology will double its effectiveness *every 8 months*.



CT18. The number of electrons per unit volume per unit energy, $n(E)$, is $f(E)g_c(E)$, where

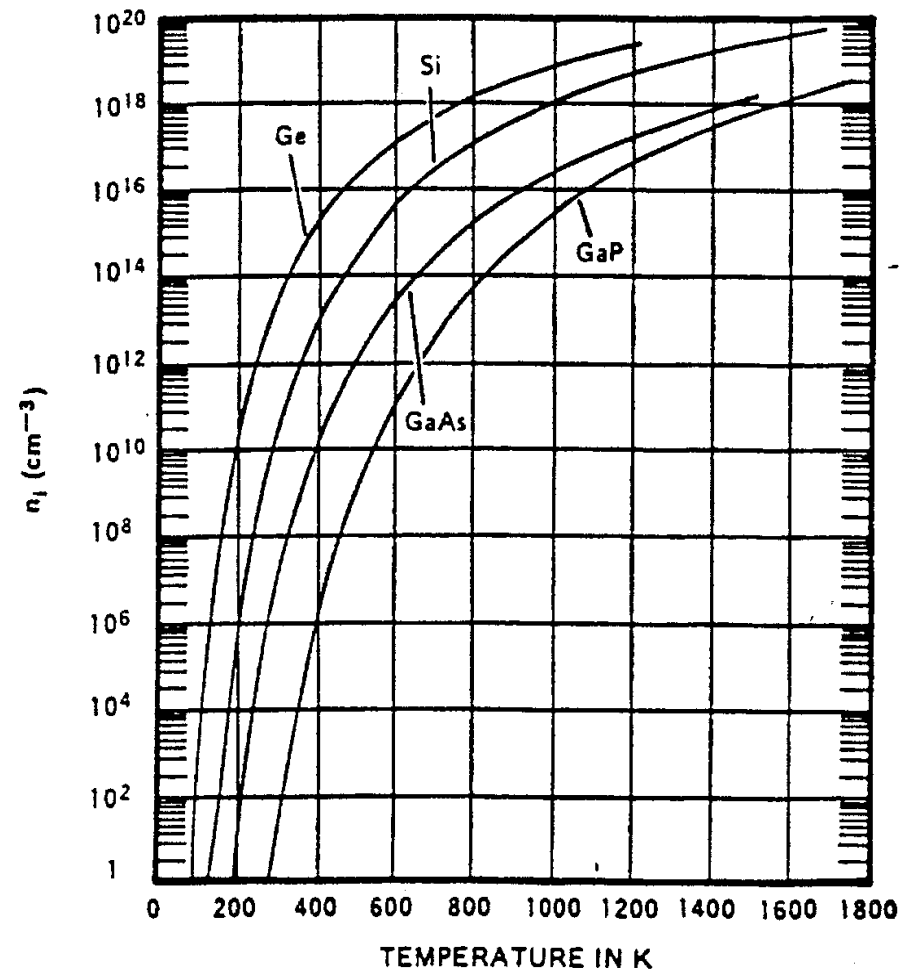
(A) $g_c(E) = [4\pi(2m_n^*)^{3/2} / h^3] \sqrt{E - E_c}$ is the number of quantum states in the conduction band per unit volume per unit energy and $f(E) = 1 / \{1 + \exp[(E - E_F) / (kT)]\}$ is called the Fermi-Dirac distribution function and gives the probability that an allowed quantum state at the energy E is occupied by an electron.

or **(B)** $f(E) = 1 / \{1 + \exp[(E - E_F) / (kT)]\}$ is the number of quantum states in the conduction band per unit volume per unit energy and $g_c(E) = [4\pi(2m_n^*)^{3/2} / h^3] \sqrt{E - E_c}$ is called the Fermi-Dirac distribution function and gives the probability that an allowed quantum state at the energy E is occupied by an electron.

CT19.

At the same temperature, $n_i(\text{Ge})$ is higher than $n_i(\text{Si})$, because:

- (A) Ge is cheaper.
- (B) The temperatures for both materials are not the exact same.
- (C) Energy gap of Si is bigger.
- (D) Energy gap of Si is smaller.

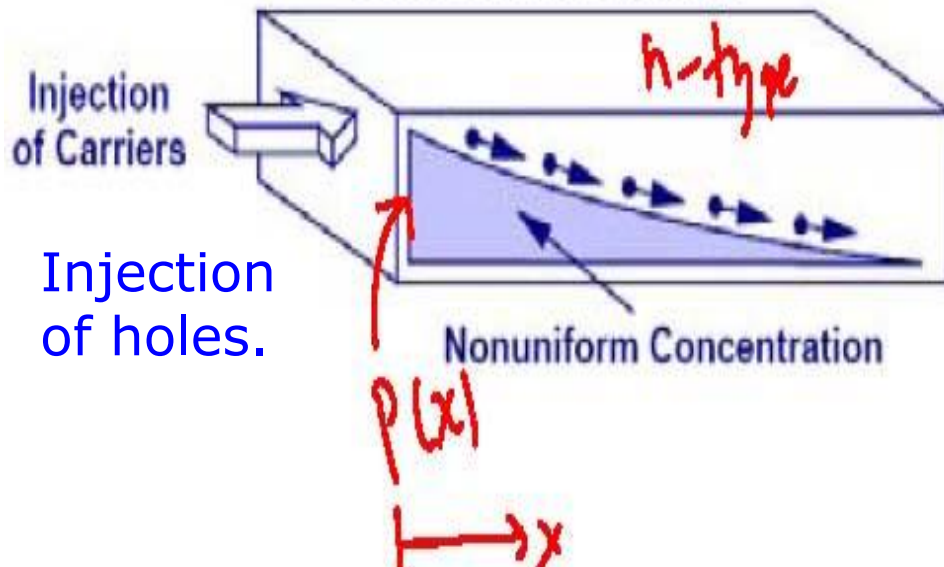


CT20. Hole diffusion current is at

(A) opposite x direction.

(B) positive x direction.

$$J_p = -qD_p \frac{dp}{dx}$$



Notation:

$D_p \equiv$ hole diffusion constant (cm^2/s)

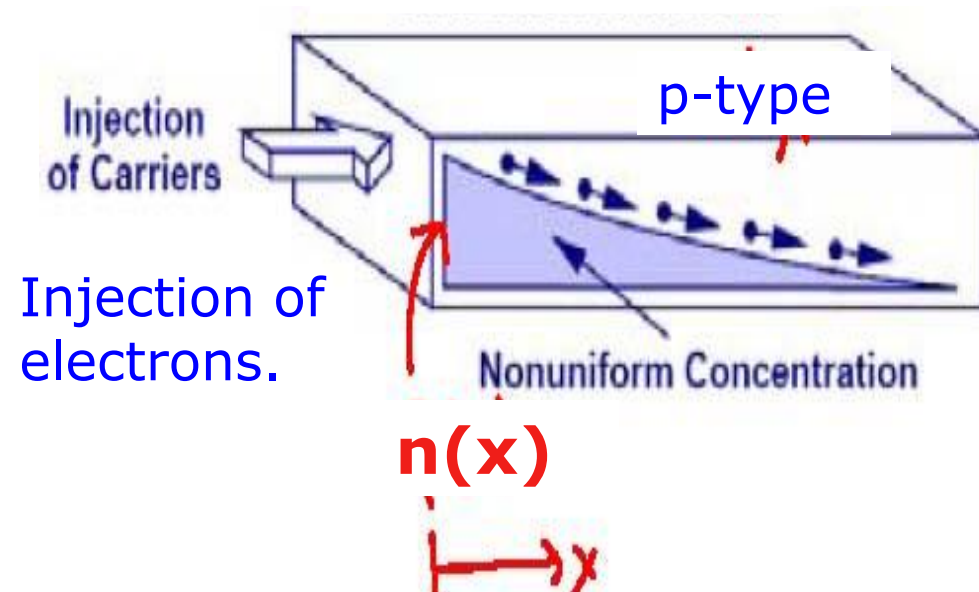
$D_n \equiv$ electron diffusion constant (cm^2/s)

CT21. Electron diffusion current is at

(A) opposite x direction.

(B) positive x direction.

$$J_n = qD_n \frac{dn}{dx}$$



Notation:

$D_p \equiv$ hole diffusion constant (cm^2/s)

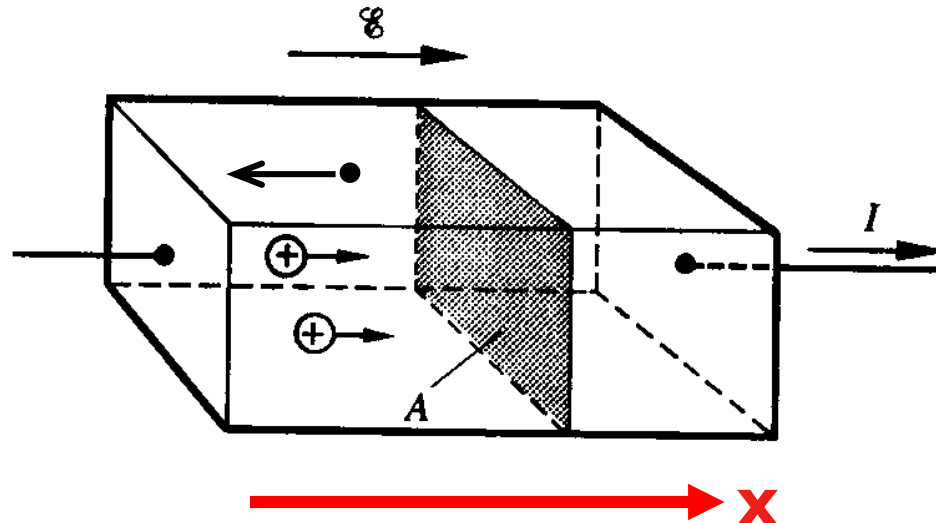
$D_n \equiv$ electron diffusion constant (cm^2/s)

CT22. Hole drift current is

- (A) at opposite x direction.
- (B) at positive x direction.
- (C) zero.

hole current density: $J_p = (+q) p v_h = q p \mu_p E$

p-type
Silicon

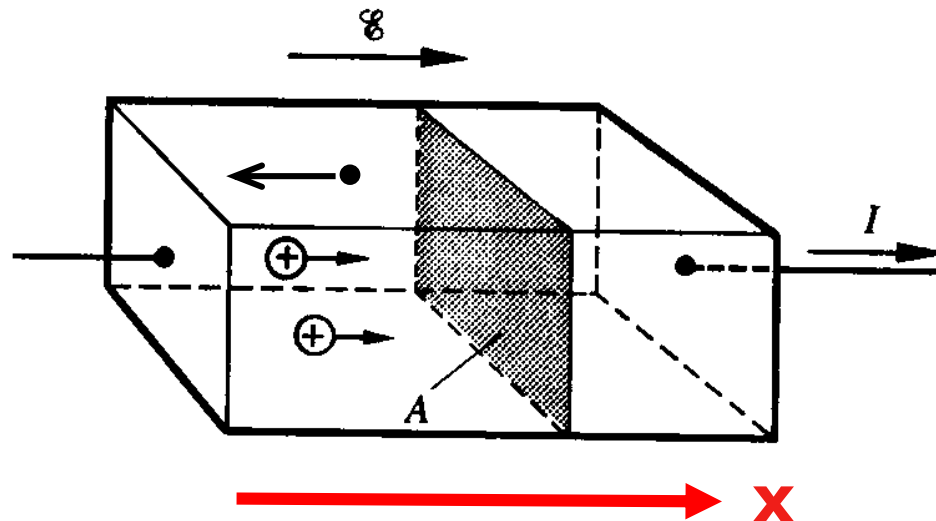


CT23. Electron drift current is

- (A) at opposite x direction.
- (B) at positive x direction.
- (C) zero.

electron current density: $J_n = (-q)nv_e = qn\mu_n E$

p-type
Silicon



CT24. On the relation: $\rho \equiv \frac{1}{\sigma} = \frac{1}{qn\mu_n + qp\mu_p}$ (ohm•cm)

- (A) ρ is resistivity, σ is conductivity and μ is mobility.
 - (B) ρ is resistivity, μ is conductivity and σ is mobility.
 - (C) σ is resistivity, ρ is conductivity and μ is mobility.
-

CT25. Which one is true ?

- (A) **Generation** is a process of creating electron-hole pairs and exciting an electron from the valence band to the conduction band is referred to as **recombination**.
- (B) **Recombination** is a process by which an electron from conduction band is moved to the valence band, and *annihilating* an electron-hole pairs is referred to as **generation**.
- (C) **Recombination** is a process by which an electron from conduction band is moved to the valence band, and exciting an electron from valence band to conduction band is referred to as **generation**.